

PRC 6625™

Back Side Reticle Cleaner

COAT ■ DEVELOP ■ BAKE ■ WEE

The PRC 6625™ (patent pending) provides a means of cleaning the back side of a Pelliculized Reticle without affecting nor even touching the Pelliculized side of the reticle.

The specially designed handling means coupled with an innovative capture chuck enables the cleaning of the back to remove unwanted haze and particles. The tool typically handles the reticles from a SMIF pod and returns the cleaned reticle to the SMIF pod.

The use of the S-Cubed PRC 6625 will substantially reduce reticle set costs by providing means for a fab to clean their reticles without having to resort to sending the reticles out for pellicle demount, clean and remount.

Features

- Mask handling is only at points on the edge
- Pellicle does not need to be removed
- Clears haze
- Remove organic and particulate contamination
- Self contained Class I environment when used with a SMIF pod



S-Cubed System Features

- Small footprint
- Color LCD touchscreen
- One or two spin modules
- Unlimited process storage capabilities
- Remote data collection and control
- Stacked thermal modules
- Multiple size substrates without change
- Servo motion control
- Process substrates up to 300 mm
- Proven modular design
- Ultra high reliability

For more information on all products including the new Flexi III™ system, the TruClean™ double sided scrubbing systems, and Cyclone™ spin processors, please visit our website: www.s-cubed.com.

S CUBED

Solid • Smart • Stable

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